

ABSTRACT

An apparatus includes semiconductor processing equipment. A particle detecting integrated circuit is positioned in a vacuum environment, the particle detecting
5 integrated circuit containing a device having a pair of conductive lines exposed to the vacuum environment. The pair of conductive lines is spaced at a critical pitch corresponding to diameters of particles of interest. A computer system is linked to the particle detecting
10 integrated circuit to detect a change in an electrical property of the conductive lines when a particle becomes lodged between or on the lines.

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